

# Eldwin J Ng

## List of Publications by Year in descending order

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19  
papers

681  
citations

933447

10  
h-index

1125743

13  
g-index

19  
all docs

19  
docs citations

19  
times ranked

608  
citing authors

#	ARTICLE	IF	CITATIONS
1	Fatigue Experiments on Single Crystal Silicon in an Oxygen-Free Environment. Journal of Microelectromechanical Systems, 2015, 24, 351-359.	2.5	129
2	Temperature Dependence of the Elastic Constants of Doped Silicon. Journal of Microelectromechanical Systems, 2015, 24, 730-741.	2.5	109
3	A Unified Epi-Seal Process for Fabrication of High-Stability Microelectromechanical Devices. Journal of Microelectromechanical Systems, 2016, 25, 489-497.	2.5	107
4	Mode-Matching of Wineglass Mode Disk Resonator Gyroscope in (100) Single Crystal Silicon. Journal of Microelectromechanical Systems, 2015, 24, 343-350.	2.5	102
5	Direct Detection of Akhiezer Damping in a Silicon MEMS Resonator. Scientific Reports, 2019, 9, 2244.	3.3	48
6	Nonlinearity of Degenerately Doped Bulk-Mode Silicon MEMS Resonators. Journal of Microelectromechanical Systems, 2016, 25, 859-869.	2.5	41
7	Stability of Silicon Microelectromechanical Systems Resonant Thermometers. IEEE Sensors Journal, 2013, 13, 987-993.	4.7	36
8	Experimental Investigation Into Stiction Forces and Dynamic Mechanical Anti-Stiction Solutions in Ultra-Clean Encapsulated MEMS Devices. Journal of Microelectromechanical Systems, 2016, 25, 469-478.	2.5	22
9	Characterization of Oxide-Coated Polysilicon Disk Resonator Gyroscope Within a Wafer-Scale Encapsulation Process. Journal of Microelectromechanical Systems, 2015, 24, 1687-1694.	2.5	17
10	Fabrication and Characterization of a Vacuum Encapsulated Curved Beam Switch for Harsh Environment Application. Journal of Microelectromechanical Systems, 2014, 23, 1121-1130.	2.5	16
11	Characterization of stiction forces in ultra-clean encapsulated MEMS devices. , 2014, , .		9
12	Stability measurements of silicon MEMS resonant thermometers. , 2011, , .		8
13	A unified epi-seal process for resonators and inertial sensors. , 2015, , .		8
14	Investigation of a Vacuum Encapsulated Si-to-Si Contact Microswitch Operated From $\sim 60\text{ }^{\circ}\text{C}$ to $400\text{ }^{\circ}\text{C}$ . Journal of Microelectromechanical Systems, 2015, 24, 1906-1915.	2.5	8
15	Micro-Tethering for Fabrication of Encapsulated Inertial Sensors With High Sensitivity. Journal of Microelectromechanical Systems, 2019, 28, 372-381.	2.5	7
16	Tunable quality factor through 1:1 modal coupling in a disk resonator. , 2015, , .		6
17	Autonomous calibration of MEMS disk resonating gyroscope for improved sensor performance. , 2016, , .		5
18	Stable Encapsulated Charge-Biased Resonators. Journal of Microelectromechanical Systems, 2016, 25, 30-37.	2.5	3

#	ARTICLE	IF	CITATIONS
19	Erratum to "Temperature Dependence of the Elastic Constants of Doped Silicon" [Jun 15 730-741]. Journal of Microelectromechanical Systems, 2015, 24, 2178-2178.	2.5	0